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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

: Confirmation No. 1190

Seiji KATSUOKA et al.

: Docket No. 2003-1648A

Serial No. 10/712,348

: Group Art Unit 1734

Filed November 14, 2003

: Examiner Laura Estelle Edwards

SUBSTRATE PROCESSING APPARATUS
AND SUBSTRATE PROCESSING METHOD

THE COMMISSIONER IS AUTHORIZED
TO CHARGE ANY DEFICIENCY IN THE
FEE FOR THIS PAPER TO DEPOSIT
ACCOUNT NO. 23-0975.

RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

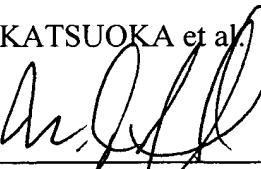
Sir:

In response to the Restriction Requirement of November 2, 2004, Applicants hereby elect the invention of Group IV, claims 7, 9, 10, 18, 19, 22, 23, 28, 29, and 33, drawn to a fourth closed lid type plating apparatus, without traverse, for further prosecution.

In view of this election, a full examination on the merits of the present application is respectfully requested.

Respectfully submitted,

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